SPECIFICATION AMENDMENTS

Please amend the title of the application to read as follows:

WAVELENGTH MULT~~IPLEXER~~/DEMULTIPLEXER

Please replace paragraph [0035] with the following:

[0035]   As above, the thickness of the dielectric multilayer film 5 is 30µm and that of the substrate 51 is 5µm, so the dielectric multilayer film 5 and the substrate 51 are inserted into the groove 4. Therefore, the half of total thickness of 30µm + 5µm = 35µm (17.5µm) is the distance from the multilayer surface 5s to the center of the <u>dielectric multilayer filter including the substrate 51</u> [[groove 4]]. Also, since the distance X from the multilayer film surface 5s to the intersection point C1 of the optical waveguides is 6µm, the distance from the intersection point C1 of the optical waveguides to the center of the <u>dielectric multiplayer filter including the substrate 51</u> [[groove 4]] is 17.5µm - 6µm = 11.5µm.

Please replace paragraph [0036] with the following:

[0036]   That is, the center of the <u>dielectric multiplayer filter including the substrate 51</u> [[groove 4]] is positioned at a distance of 11.5µm apart from the intersection point C1 of the optical waveguides, and the groove 4 is arranged to be perpendicular to the perpendicular bisector of the optical waveguides 2 and 3 and with a wider width than the total thickness of the dielectric multilayer film 5 by 2µm to 3µm.

Please replace paragraph [0053] with the following:

[0053]   For the demultiplexing characteristic obtained by the reflection from the optical waveguide 2 to the optical waveguide 3, a flat and low-loss characteristic is obtained in the longer wavelength than 1550 nm [[μm]], shows as shown in FIG. 4, and the problem in the prior art, the increased loss in the long wavelength band is solved.

Please replace paragraph [0059] with the following:

[0059]   In the experiment, the set position of the dielectric multilayer film 5 is changed from the position where the intersection point C1 is set at the multilayer film surface 5s (distance "X = 0" in FIG. 2A) to the position where the intersection point C1 is set at the boundary of the dielectric multilayer film 5 and the substrate 51 (distance "X = d" in FIG. 2C [[2B]]). The dielectric multilayer filter 5 is a short wavelength pass filter having an alternating multilayer of SiO_2 and Ta_2O_5 with a thickness of 30μm stacked on a polyimide thin-film substrate (substrate 51) with a thickness of 5μm, and its edge wavelength of the stop (reflection) band is set around 1530nm.